



ITW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 7391**
Tatsuya SASAKI et al. : Attorney Docket No. 2005_1908A
Serial No. 10/559,815 : Group Art Unit 1792
Filed March 23, 2006 : Examiner Sylvia MacArthur

POLISHING APPARATUS AND POLISHING
METHOD :

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to the requirement contained in the Office Action mailed June 25, 2008, applicants hereby elect Species I, claims 1-8.

In view of this election, a full examination on the merits of the present application is respectfully requested.

Respectfully submitted,

Tatsuya SASAKI et al.

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